

Rapid prototyping of silicon structures by aid of laser and abrasive-jet machining

Kruusing, Arvi; Leppävuori, Seppo; Uusimäki, Antti; Uusimäki, M. Design, Test and Microfabrication of MEMS and MOEMS : 30

March-1 April, 1999, Paris, France 1999 / p. 870-878 : ill <https://opticalengineering.spiedigitallibrary.org/conference-proceedings-of-spie/3680/0000/Rapid-prototyping-of-silicon-structures-by-aid-of-laser-and/10.1117/12.341285.full>